

Notice of References Cited	Application/Control No. 10/734,812	Applicant(s)/Patent Under Reexamination JARDINE, PETER A.	
	Examiner John J. Zimmerman	Art Unit 1775	Page 1 of 2

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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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